

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Thomas N. Horsky
Serial No.: _____
Filed: _____
Title: Electron Impact Ion
 Source
Group Art Unit: N/A
Examiner: N/A

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MAIL STOP PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
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Information Disclosure Statement

Dear Sir:

Pursuant to the provisions of 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicant submits a Form PTO-1449 and documents other than U.S. patents and published U.S. patent applications listed on Form PTO-1449. These documents identified on Form PTO-1449 are for consideration during the prosecution of the subject application. This document is being filed in accordance with 37 C.F.R. §§ 1.97(b) and before the first Official Action.

The Commissioner is hereby authorized to charge any additional fees which may be required with respect to this communication or credit any overpayment to Deposit Account No. 50-1214.

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The above constitutes information that an Examiner may find material to the examination of the subject application; however, it does not negate the patentability of the subject invention. Furthermore, it is not intended that submission of this information be taken as a representation that a search has been made or that no information which is more material exists.

Respectfully submitted,

Katten Muchin Zavis Rosenman

Date: 12-30-03

By: 

John S. Paniaguas

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Form PTO-1449								Docket Number 211843-00022		Application Number 10/183,768				
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)								Applicant Thomas Horsky						
								Filing Date June 26, 2002		Group Art Unit 2881				
U. S. PATENT DOCUMENTS														
EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROP.		
	6	4	5	2	3	3	8	9/17/02	Horsky					
	6	2	8	8	4	0	3	9/11/01	Horsky et al.					
	3	5	8	1	1	9	5	6/10/68	Robert L. Jepsen					
	5	5	4	3	6	2	5	8/6/96	Johnson et al.					
	6	3	5	2	6	2	6	3/5/02	von Zweck					
	4	7	4	0	6	9	8	4/26/88	Tamura et al.					
	4	2	1	7	8	5	5	8/19/80	Takagi					
	4	1	5	2	4	7	8	5/1/79	Takagi					
	3	5	5	7	3	6	5	12/22/67	Ralph Elliott Mayo Fairfield; Edward B. Delany, Ridgefield, Conn.					
	4	1	2	0	7	0	0	10/17/78	Morimoto					
	5	5	6	1	3	2	6	10/1/96	Ito et al.					
	5	6	8	6	7	8	9	11/11/97	Schoenbach et al.					
	5	5	2	8	0	3	4	6/18/96	Yamazaki et al.					
	4	9	4	3	7	1	8	07/90	Haines et al.					
	4	6	4	9	2	7	8	03/87	Chutjian et al.					
FOREIGN PATENT DOCUMENTS														
	DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUB CLASS	Translation		
												Yes	No	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)														
	Thomas N. Horsky, Electron Beam Ion Source With Integral Low-Temperature Vaporizer, U.S. Patent Application Publication No. US 2002/0070672 A1 dated June 13, 2002													
	Lo et al., Method and Apparatus for Multiple Charge particle Beams, U.S. Patent Application Publication No. US 2003/0001095 A1 dated January 2, 2003													
	Brautti et al., "Trapped Ion Source", IEEE Journal 1998, pp. 2729-2731													
	Boggia et al., "Study of a Trapped Ion Source", IEEE Journal, pp. 1433-1435													
EXAMINER										DATE CONSIDERED				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.														